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AF-9

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: **Daisuke KOMADA, et al.**  
Corres. and Mail

Group Art Unit: 1756

Serial No.: 10/058,426

**BOX AF**

Examiner: **BARRECA, Nicole M.**

Filed: **January 30, 2002**

Confirmation No.: 4298

For: **METHOD OF MANUFACTURING SEMICONDUCTOR DEVICE HAVING  
SILICON CARBIDE FILM**

Attorney Docket No.: 020060

Customer Number: 38834

**PETITION FOR EXTENSION OF TIME**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Date: July 20, 2004

Sir:

Applicants petition the Commissioner for Patents to extend the time for response to the Office Action dated April 1, 2004 for one month from July 1, 2004 to August 1, 2004.

Attached please find a check in the amount of \$ 110.00 to cover the cost of the extension for a large entity. In the event that any additional fees are due in connection with this paper, please charge our Deposit Account No. 50-2866.

Respectfully submitted,

WESTERMAN, HATTORI, DANIELS & ADRIAN, LLP

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